

RCE
Zhu

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Fumio KOYAMA et al.

Application No.: 10/026,637

Filed: December 27, 2001

Group Art Unit: 2828

Examiner: Armando Rodriguez

Docket No.: 111587

For: SURFACE EMITTING SEMICONDUCTOR LASER AND MANUFACTURING METHOD THEREOF **MAIL STOP RCE**

**LARGE ENTITY REQUEST FOR
CONTINUED EXAMINATION UNDER 37 C.F.R. §1.114**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 37 C.F.R. §1.114, Applicant(s) hereby request(s) continued examination.

☒ Applicants further request entry and consideration of the attached submission.

The above-identified application was filed on or after June 8, 1995. Thus, entry is proper under 37 C.F.R. §1.114(d).

Attached hereto is our check no. 163734 in the amount of ☒ \$790.00 as payment of the fees set forth in 37 C.F.R. §1.17(e). The Commissioner is hereby authorized to charge any additional fees or credit any overpayment associated with this communication to Deposit Account No. 15-0461. Two duplicate copies of this page are enclosed.

Respectfully submitted,



James A. Oliff
Registration No. 27,075

Tarik M. Nabi
Registration No. 55,478

JAO:TMN/tje

Date: February 18, 2005

OLIFF & BERRIDGE, PLC
P.O. Box 19928
Alexandria, Virginia 22320
Telephone: (703) 836-6400

DEPOSIT ACCOUNT USE AUTHORIZATION Please grant any extension necessary for entry; Charge any fee due to our Deposit Account No. 15-0461

02/22/2005 RFEKADU1 00000048 10026637

01 FC:1801

790.00 0P